



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE  
ATTY. DOCKET NO. 14682 (RAB:rld)

Patent Application of Mohiuddin Mala, et al.

Serial No. 10/827,252

Group Art Unit: 2873

Filed: April 20, 2004

Examiner: William C. Choi

For: A MICRO-ELECTRO-MECHANICAL-SYSTEM TWO DIMENSIONAL MIRROW WITH  
ARTICULATED SUSPENSION STRUCTURES FOR HIGH FILL FACTOR ARRAYS

**INFORMATION DISCLOSURE STATEMENT**

This Information Disclosure Statement is being filed in the manner prescribed by 37 CFR 1.97(b) - (d) to satisfy the duty under 37 CFR 1.56 to disclose to the Office information, known to individuals associated with the filing and prosecution of the subject application, which is material to the examination of the application.

In accordance with 37 CFR 1.97(g) and (h), this statement is not to be construed as a representation that a search has been made or an admission that the information cited herein is, or is considered to be, material to patentability as defined in 37 CFR 1.56(b).

In compliance with 37 CFR 1.98(a)(2), also enclosed is a legible copy of:

- i) each foreign patent;
- ii) each publication or that portion which caused it to be listed; and
- iii) all other information or that portion which caused it to be listed, excluding any copies of a United States patent application.

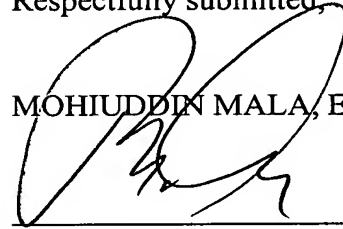
In compliance with 37 CFR 1.98(a)(1), a list of all patents, publications, applications or other information submitted for consideration by the Office is hereby provided by way of the attached Form PTO/SB/08.

It is respectfully requested that the information be expressly considered by the Examiner and that the references be made of record and appear among the "References Cited" on any patent to issue therefrom.

The Patent Office is hereby authorized to charge any deficiency, or credit any overpayment in fees to Deposit Account Number 19-2550.

Respectfully submitted,

MOHIUDDIN MALA, ET AL.



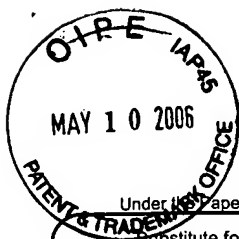
Dated: May 10, 2006

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Encls.: Form PTO/SB/08  
All references listed on Form PTO/SB/08  
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PTO/SB/08B (08-03)  
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<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> (Use as many sheets as necessary)		<b>Complete if Known</b>	
		Application Number	10/827,252
		Filing Date	April 20, 2004
		First Named Inventor	Mohiuddin Mala
		Art Unit	2873
		Examiner Name	William C. Choi
Sheet 2	of 2	Attorney Docket Number	14682

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials *	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, pages, volume-issue number(s), publisher, city and /or country where published.	T <sup>2</sup>
	AH	Johanna I. Young, et al.; COMPARATIVE STUDY OF 2-DOF MICROMIRRORS FOR PRECISION LIGHT MANIPULATION; SPIE Smart Structures and Materials Conference, Newport Beach, CA, March 4-7, 2001.	<input type="checkbox"/>
	AI	Veljko Milanovic, et al.; MONOLITHIC HIGH ASPECT RATIO TWO-AXIS OPTICAL SCANNERS IN SOI; 2003 MEMS Conference, Kyoto, Japan, January 19-23, 2003, pp. 255-258.	<input type="checkbox"/>
	AJ	Sunghoon Kwon, et al.; LARGE-DISPLACEMENT VERTICAL MICROLENS SCANNER WITH LOW DRIVING VOLTAGE; IEEE Photonics Technology Letters, Vol. 14, No. 11, November 2002, pp. 1572-1574.	<input type="checkbox"/>
	AK	D.A. Horsley et al.; MULTI-DEGREE OF FREEDOM DYNAMIC CHARACTERIZATION OF DEEP-ETCHED SILICON SUSPENSIONS; Solid State Sensor and Actuator Workshop, Hilton Head, June 4-8, 2000, pp 81-84.	<input type="checkbox"/>
	AL	B.M. Evans et al.; FINITE ELEMENT MODELING OF MICROMACHINED MEMS PHOTON DEVICES; Miniaturized Systems with Micro-optics and MEMS, Santa Clara, September 1999, SPIE 3878, pp 253-260.	<input type="checkbox"/>
	AM	David Burns, et al.; OPTICAL BEAM STEERING USING SURFACE MICROMACHINED GRATINGS AND OPTICAL PHASED ARRAYS; Optical Scanning Systems: Design and Application, San Diego, CA, July 1997, SPIE 3131, pp. 99-110.	<input type="checkbox"/>
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Examiner Signature		Date Considered	
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